

Fig. 2

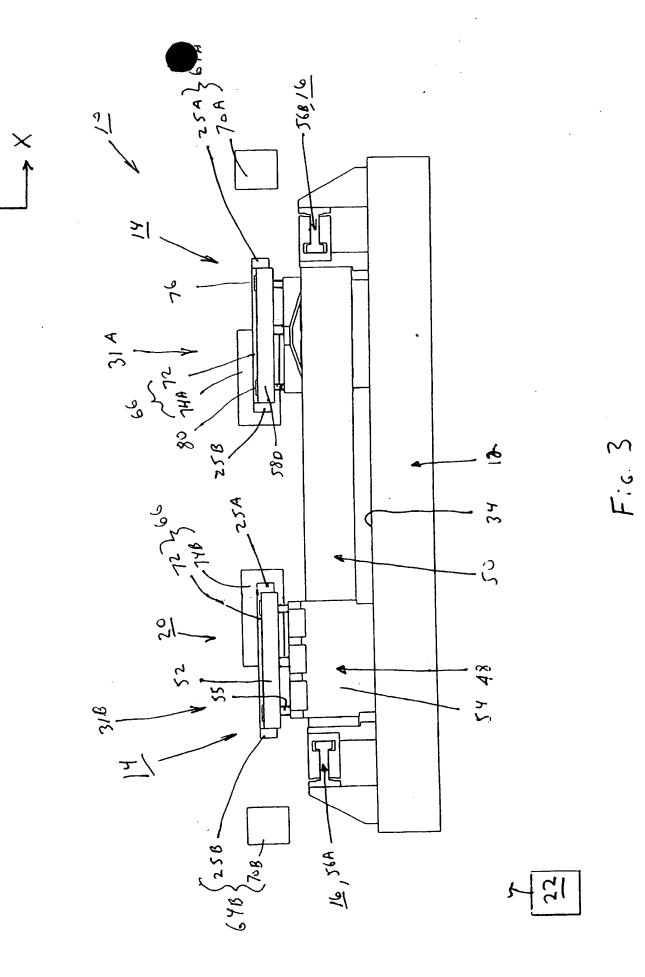
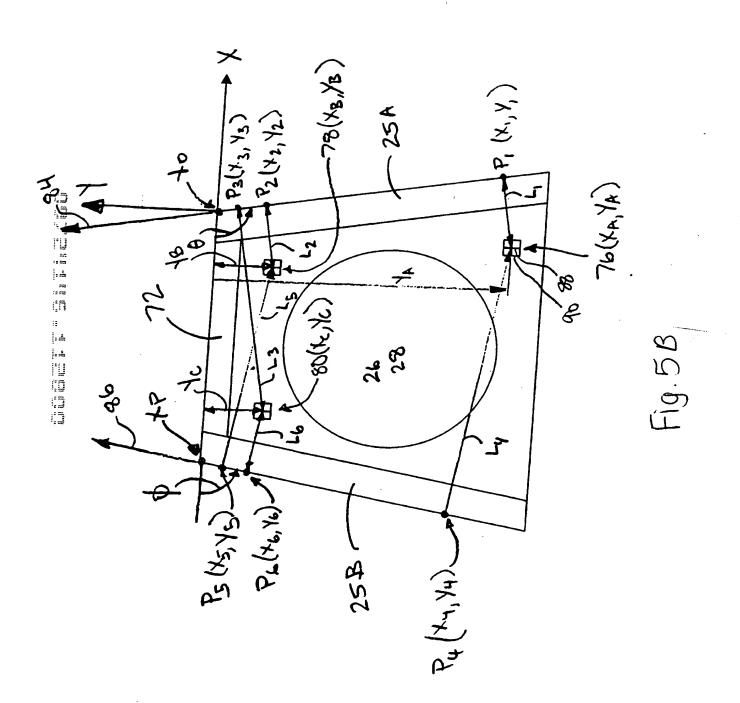
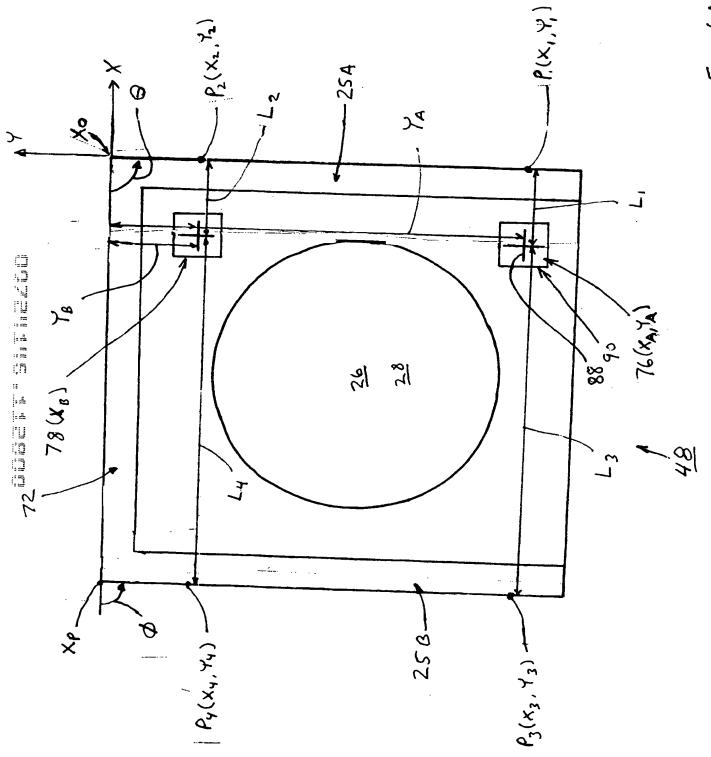


Fig. SA





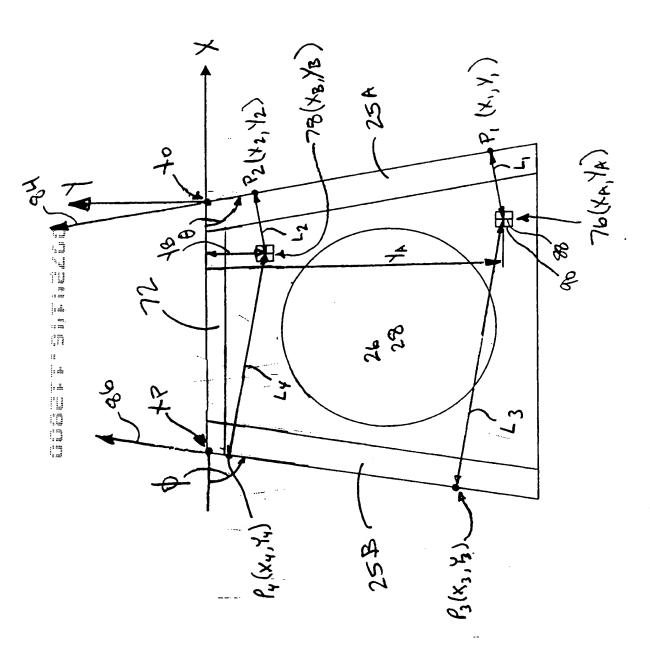
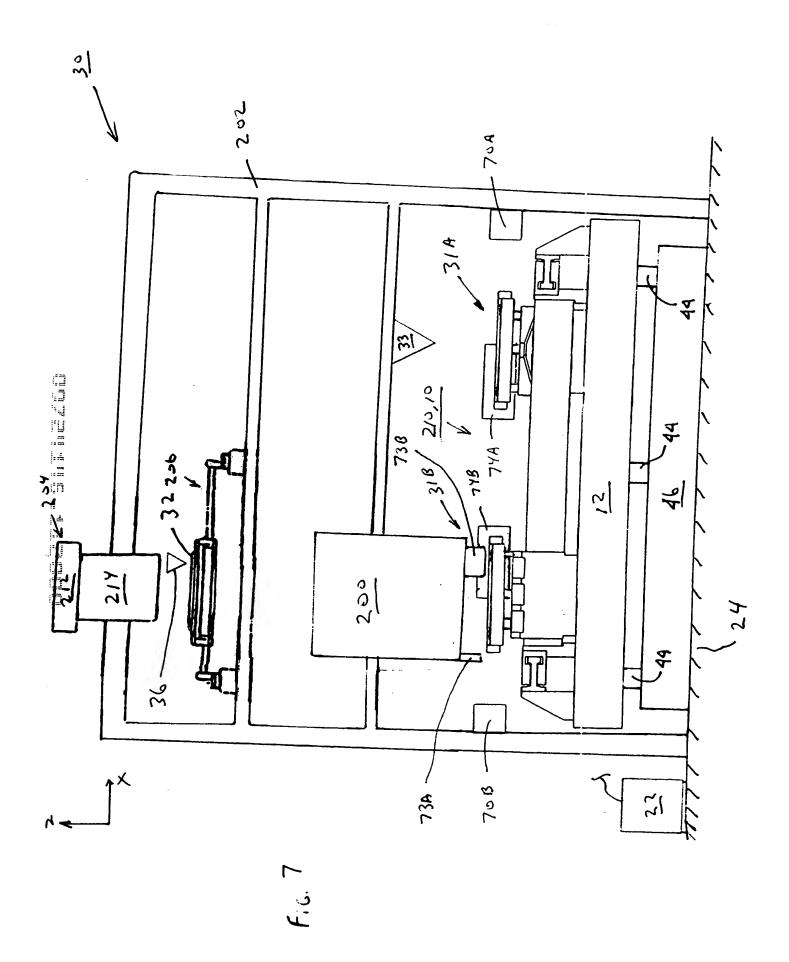
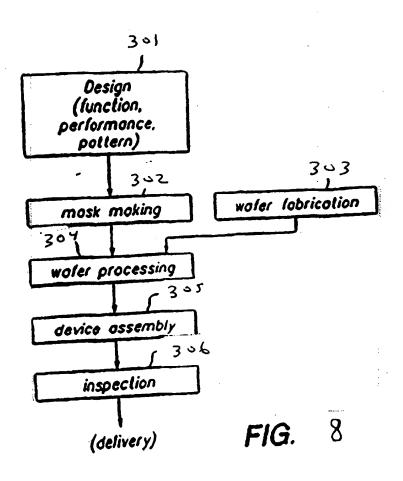


Fig. 68





3/4 Ion implentation 313 312 Electrode formation CVD Oxidation Preprocessing steps 315 Photoresist formation Post-processing steps Exposure Developing 318 .Etching 319 Photoresist removal